

Broadband spectroscopy of EUV light sources using a transmission grating spectrometer

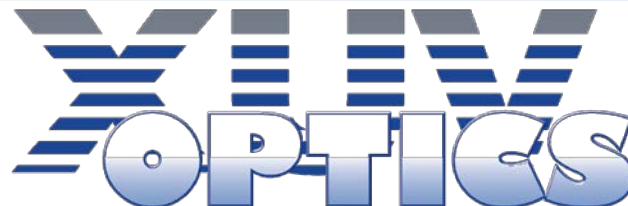
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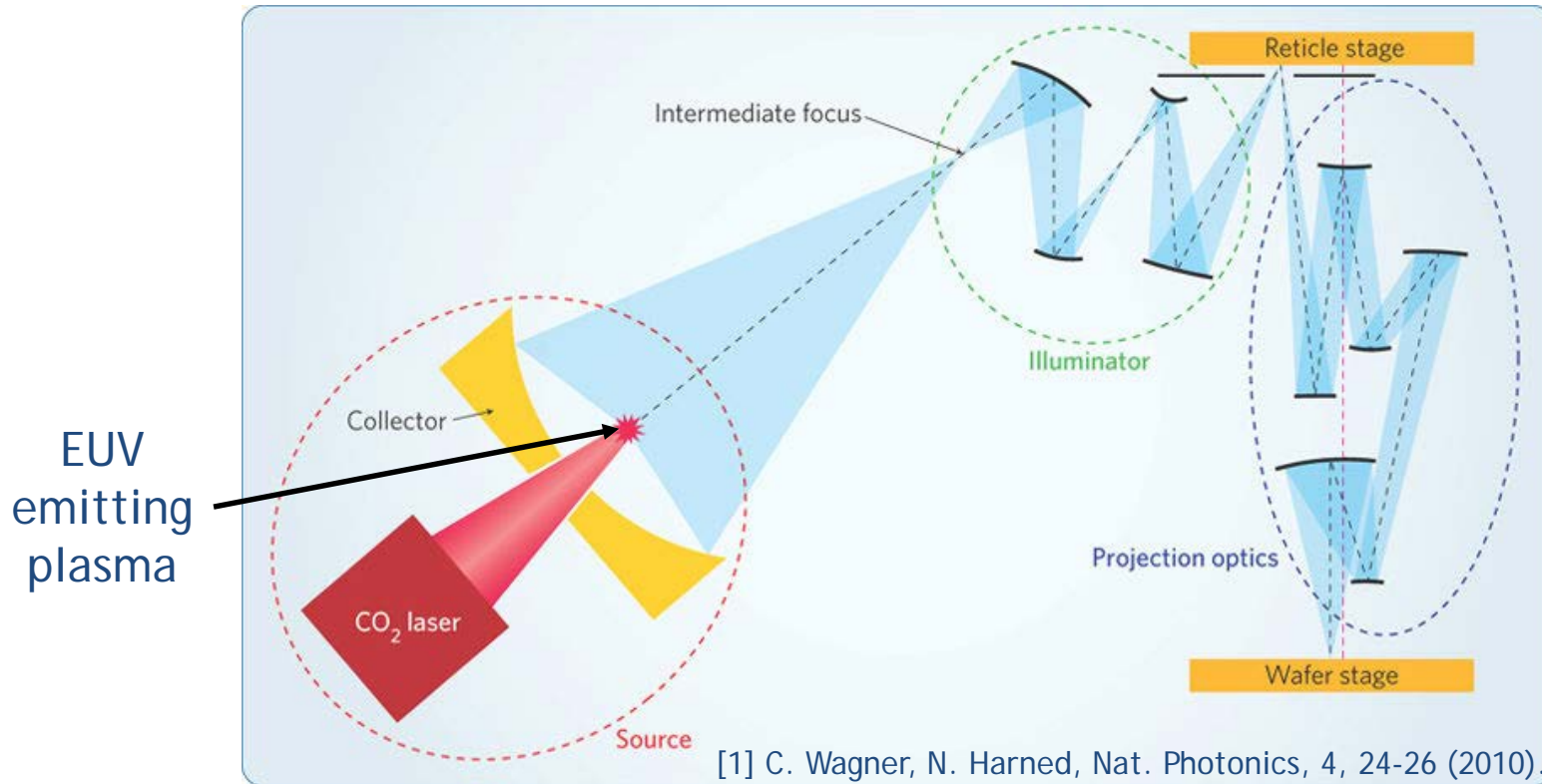
Bert Bastiaens, Fred Bijkerk (University of Twente)



Outline

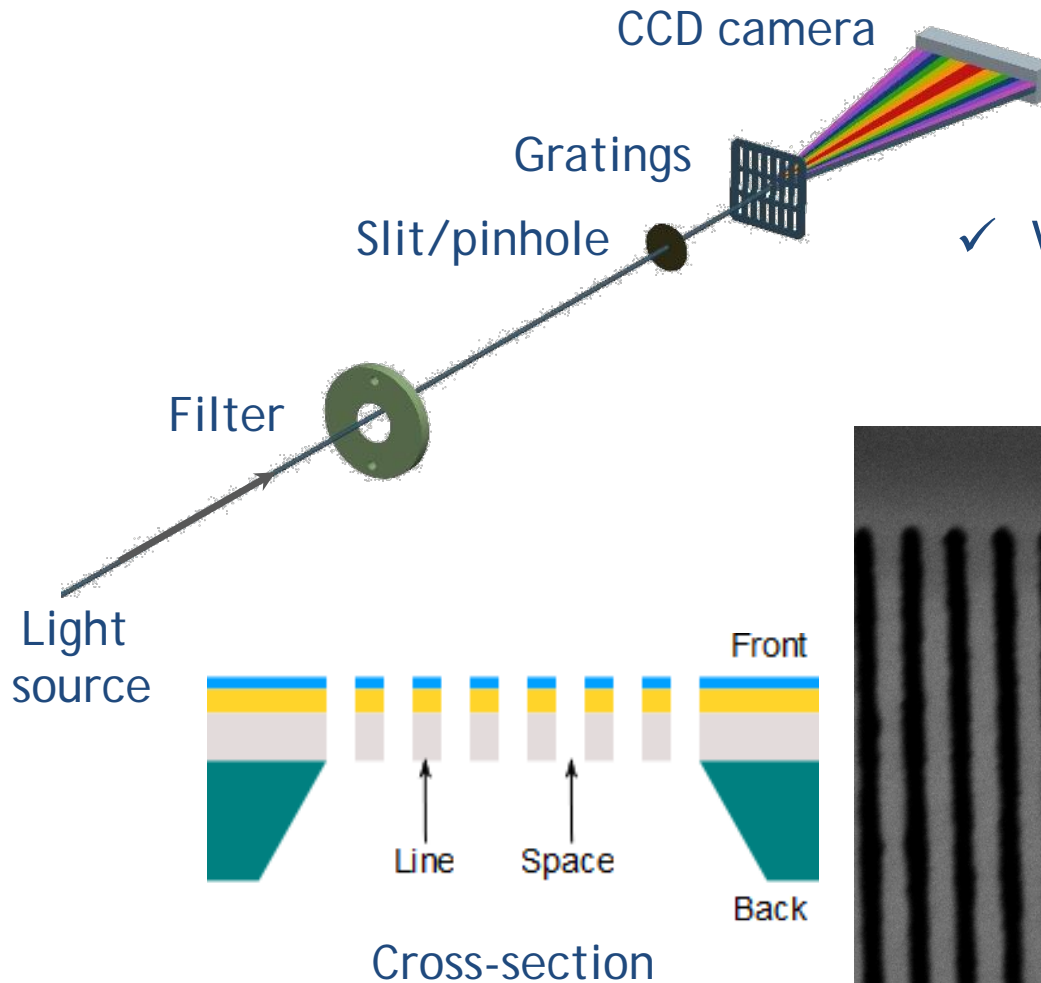
- ✓ Motivation
- ✓ XUV transmission grating spectrometer
- ✓ Nd:YAG and CO₂ laser driven plasmas
 - 1- EUV measurements
 - 2- DUV-NIR measurements
- ✓ Conclusions & outlook

Motivation

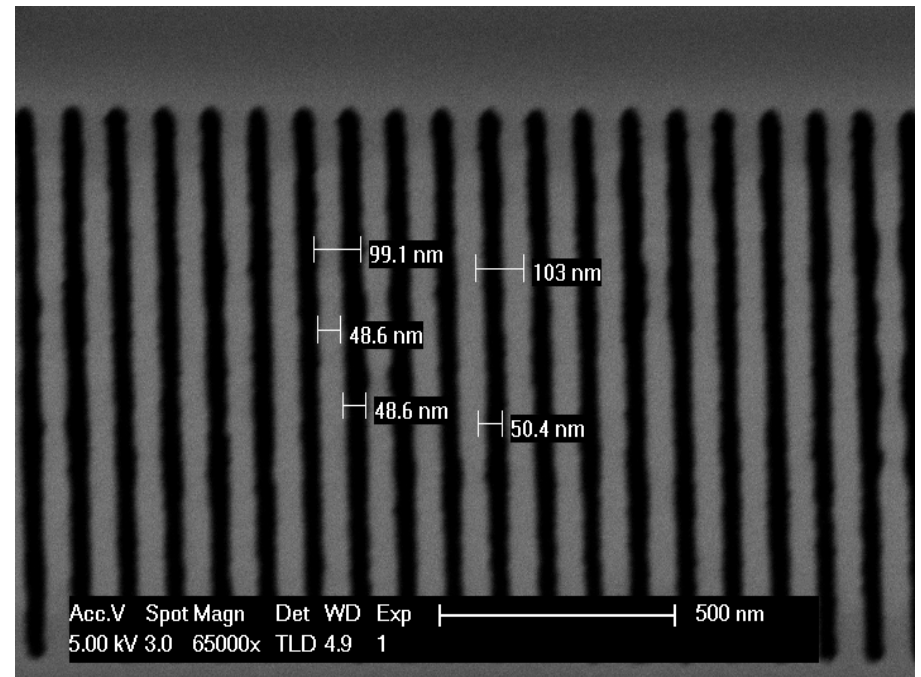


- ✓ Useful light in a narrow wavelength band: 13.5 nm ($\pm 1\%$)
- ✓ Inherent parasitic radiation in a broad spectrum
- ✓ May cause contrast loss in patterning and heat load on optics
- ✓ Need: broadband spectral monitoring

XUV transmission grating spectrometer



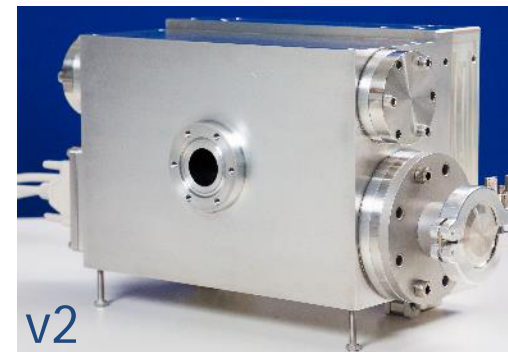
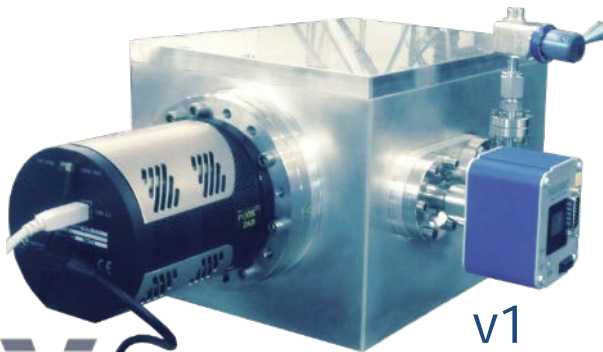
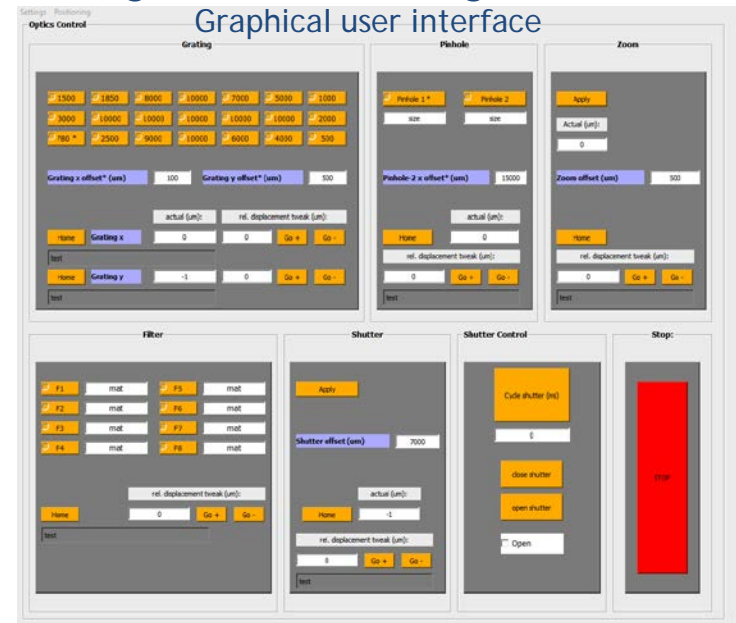
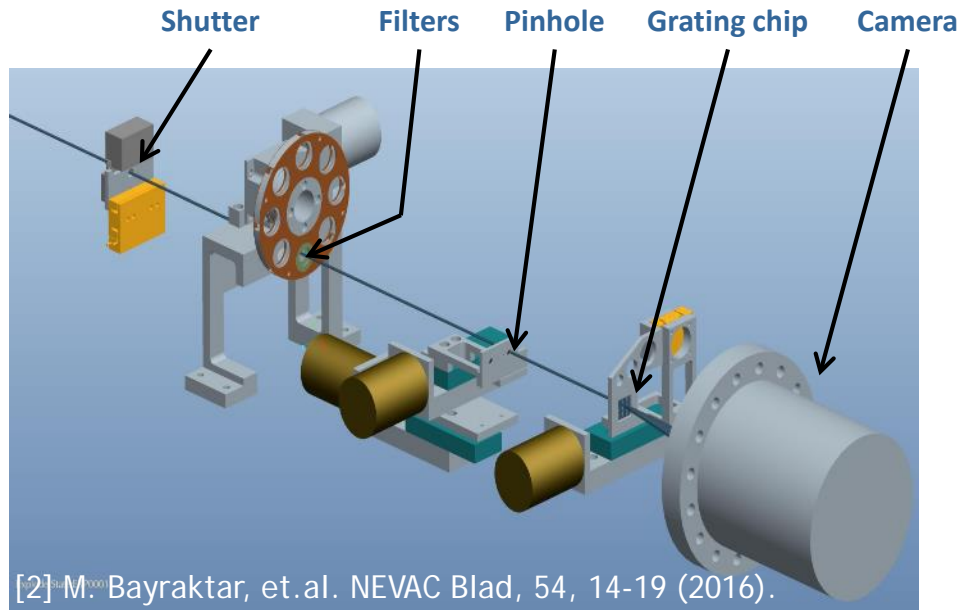
- ✓ Grating matrix
- ✓ XUV to IR range
- ✓ Very high line density
 - Up to 10.000 lines/mm
 - 0.05 nm resolution at 13.5 nm



[2] M. Bayraktar, et.al. NEVAC Blad, 54, 14-19 (2016).

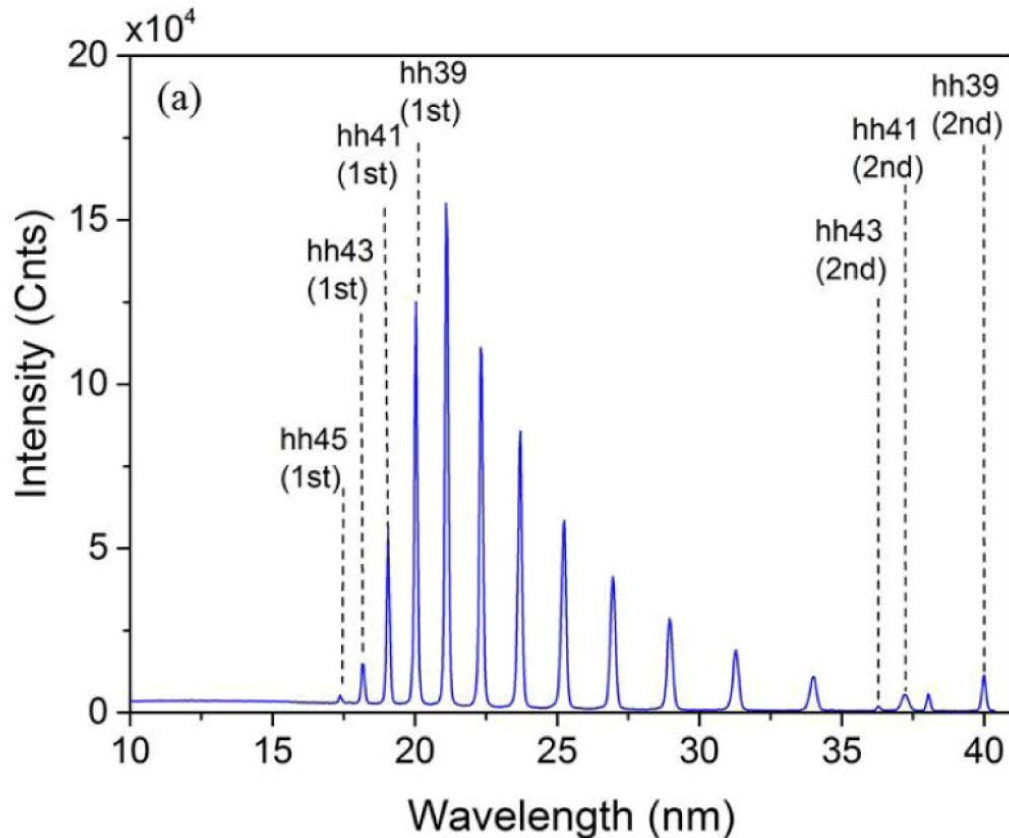
XUV transmission grating spectrometer

- ✓ Broadband coverage
- ✓ Compact design ($\sim 20 \times 25 \times 30 \text{ cm}^3$)
- ✓ Computer controlled positioning
- ✓ Straightforward alignment



XUV

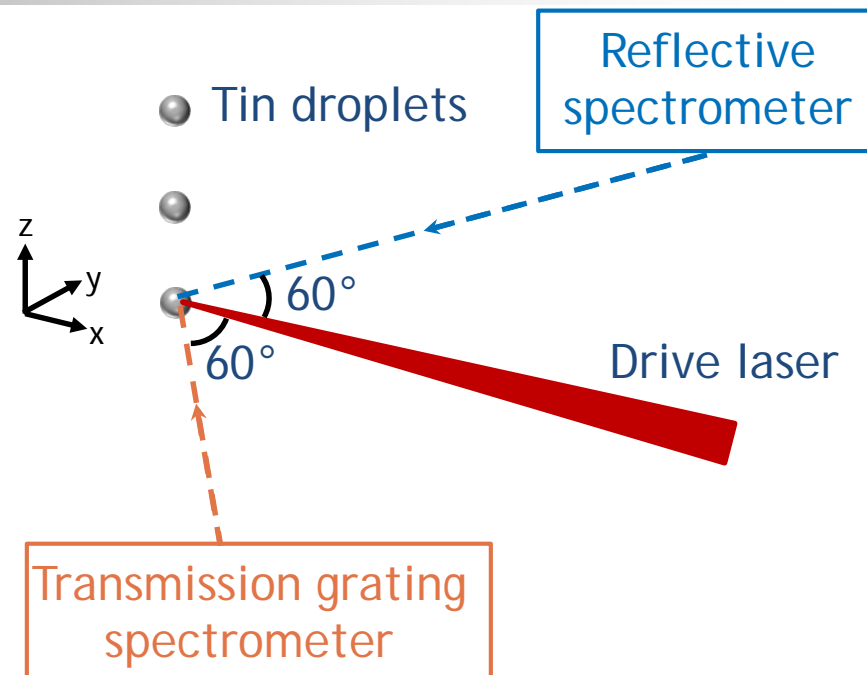
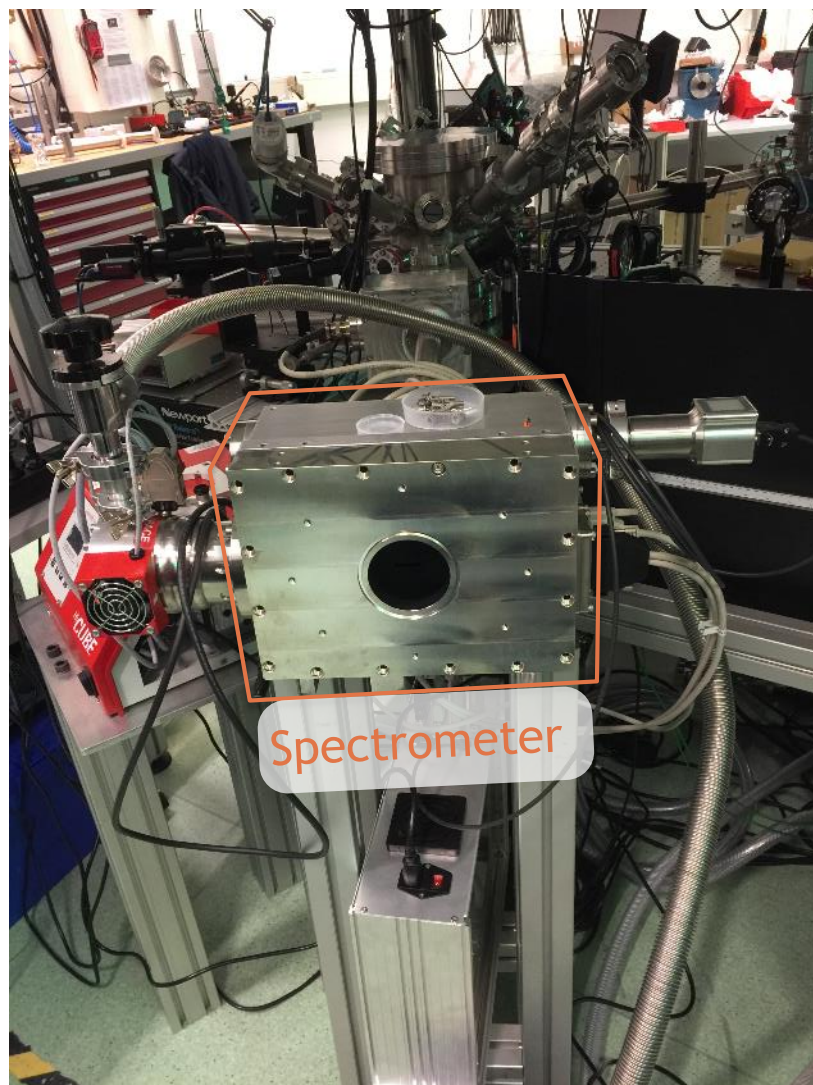
Resolution test in a HHG source



- ✓ Design resolution 0.09 nm at 21 nm (37th harmonic)
- ✓ Measured resolution < 0.13 nm^[3]
- ✓ Can be configured for 0.05 nm resolution at 13.5 nm

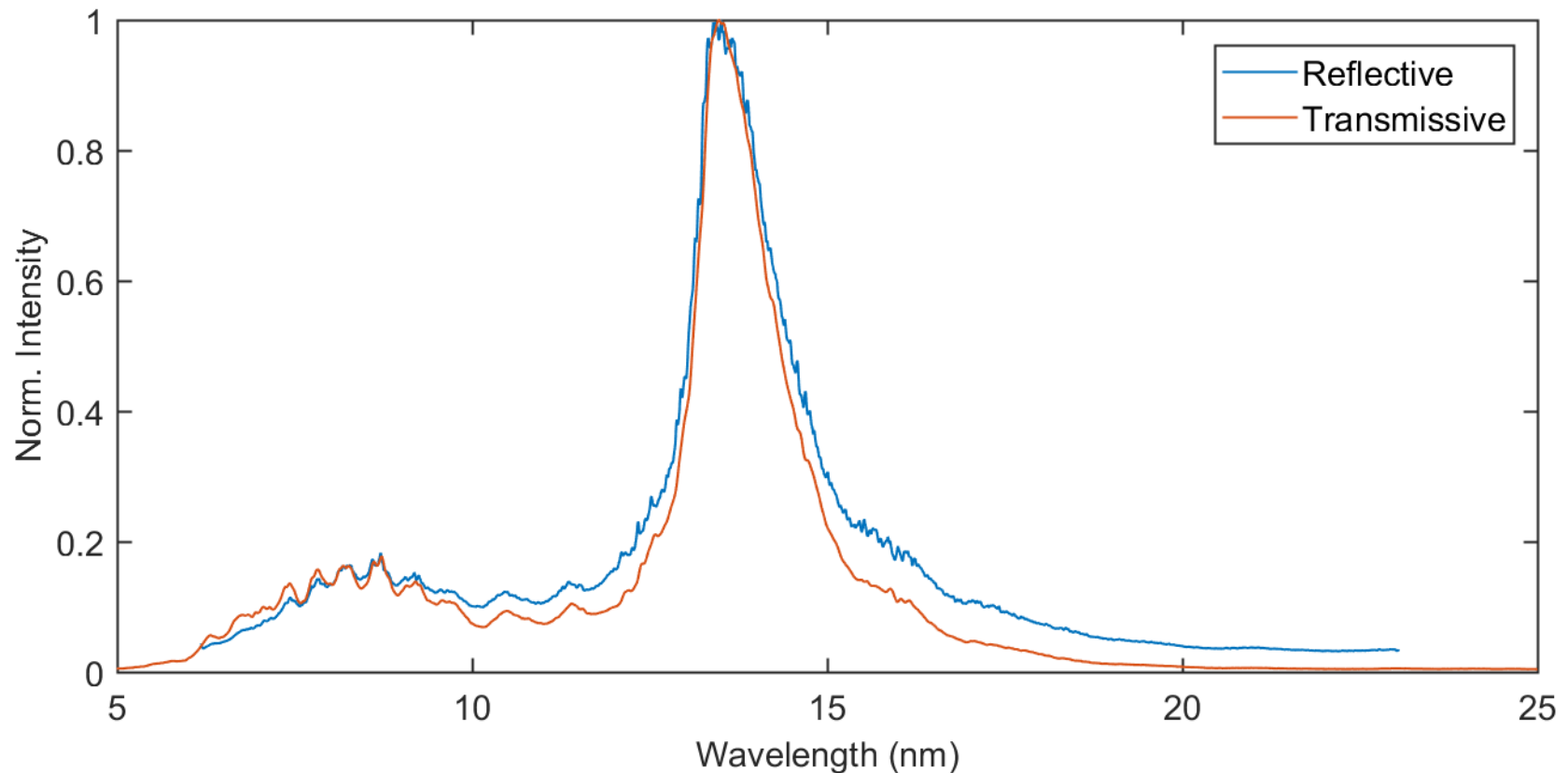
[3] J. Goh et.al. Opt. Exp. 23, 4421 (2015).

Testing of spectrometer @ARCNL



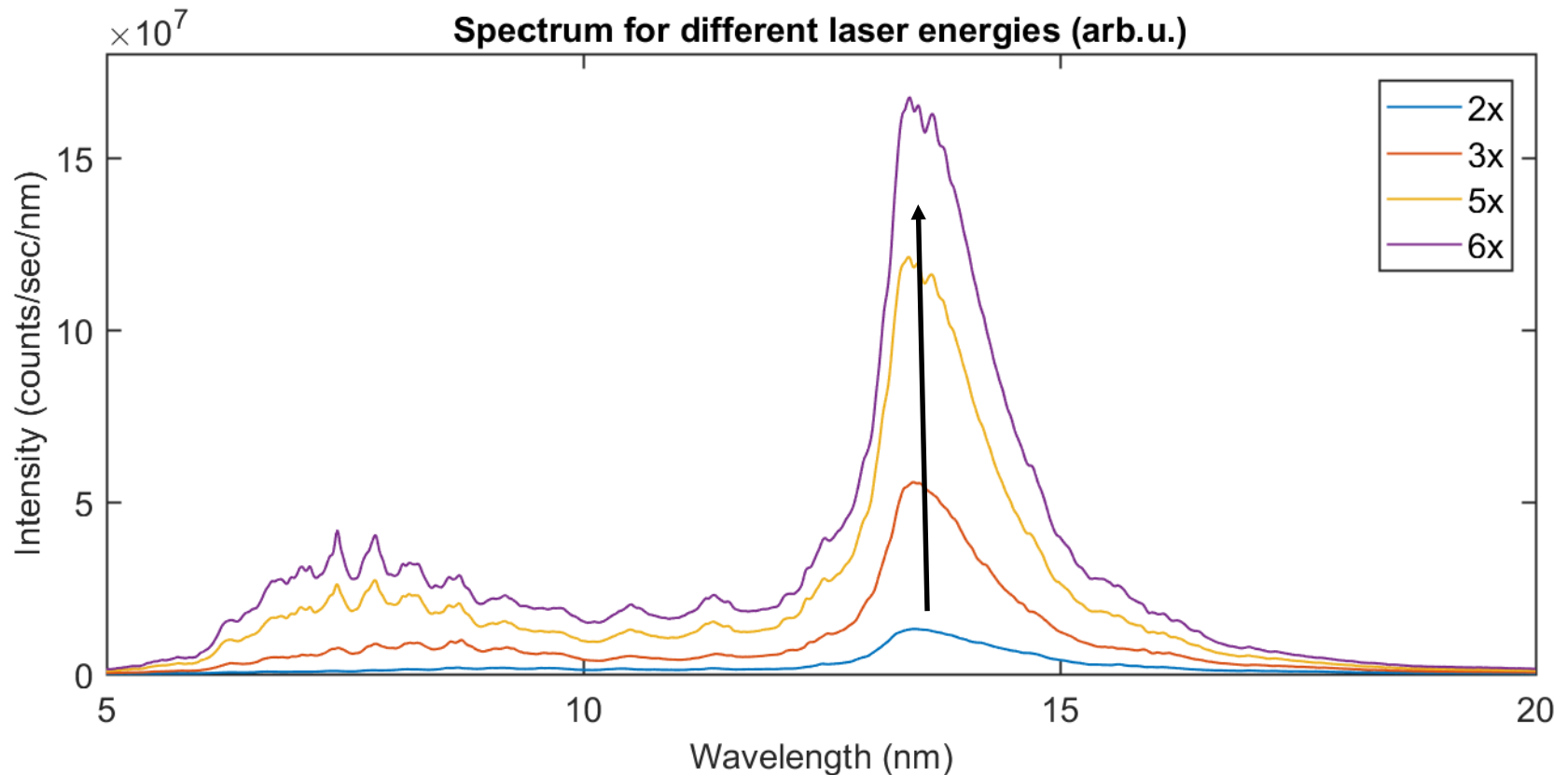
- ✓ Nd:YAG drive laser
- ✓ Gaussian pulses
- ✓ Pulse duration: 60ns
- ✓ Droplet size: $\sim 40 \mu\text{m}$
- ✓ Energy: 0.2 – 3 J

Reflective vs XUV transmissive spectrometer



- ✓ Measurements with Zr filter
- ✓ Not corrected for grating efficiency → differences in intensity
- ✓ Good matching of the peaks

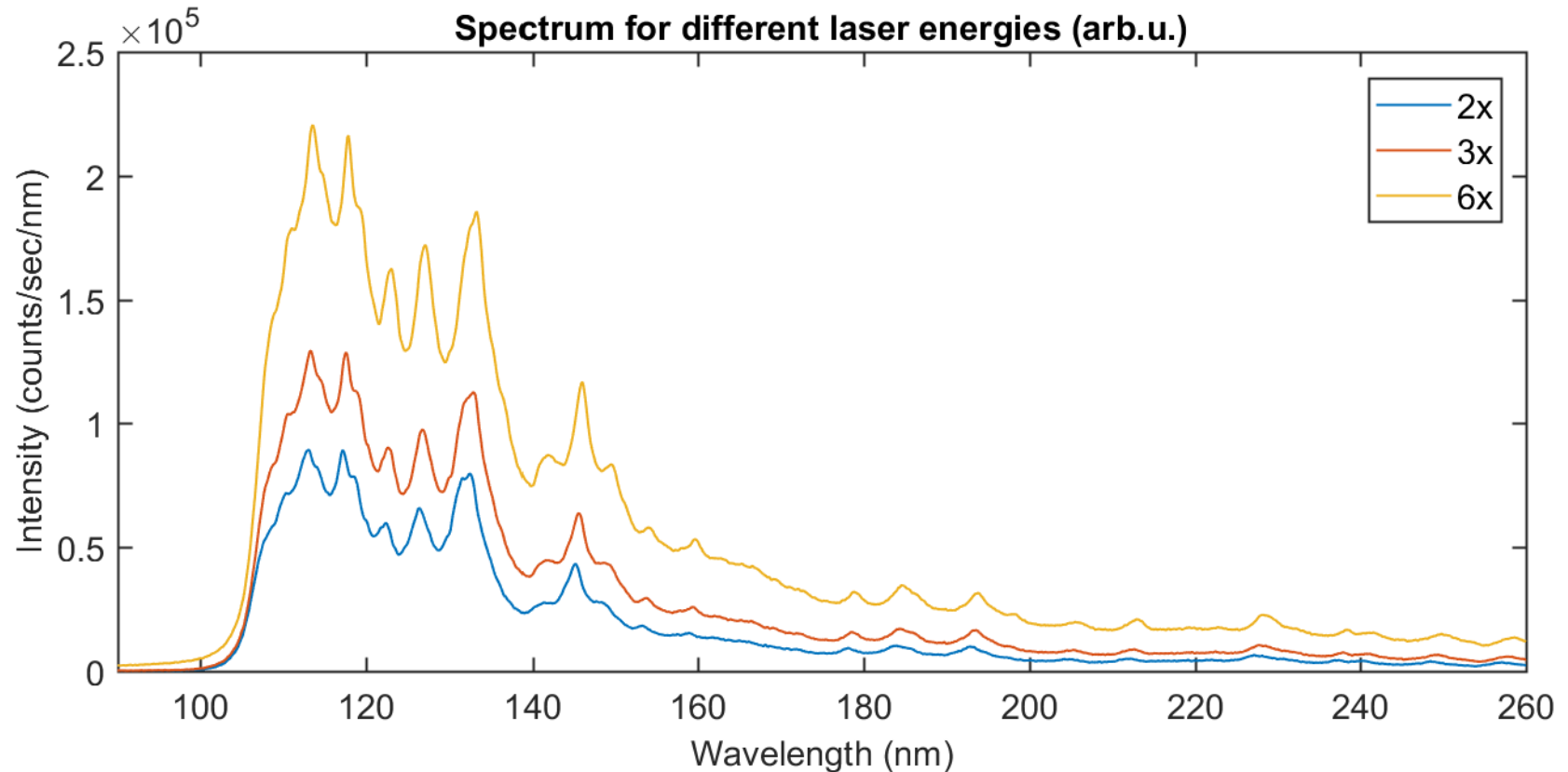
Nd:YAG laser plasma: EUV spectra



- ✓ Measured with transmission grating spectrometer
- ✓ Increased drive laser energy → higher EUV emission
- ✓ Emission below 12 nm due to higher charge states (Sn^{8+} - Sn^{15+}) [4]

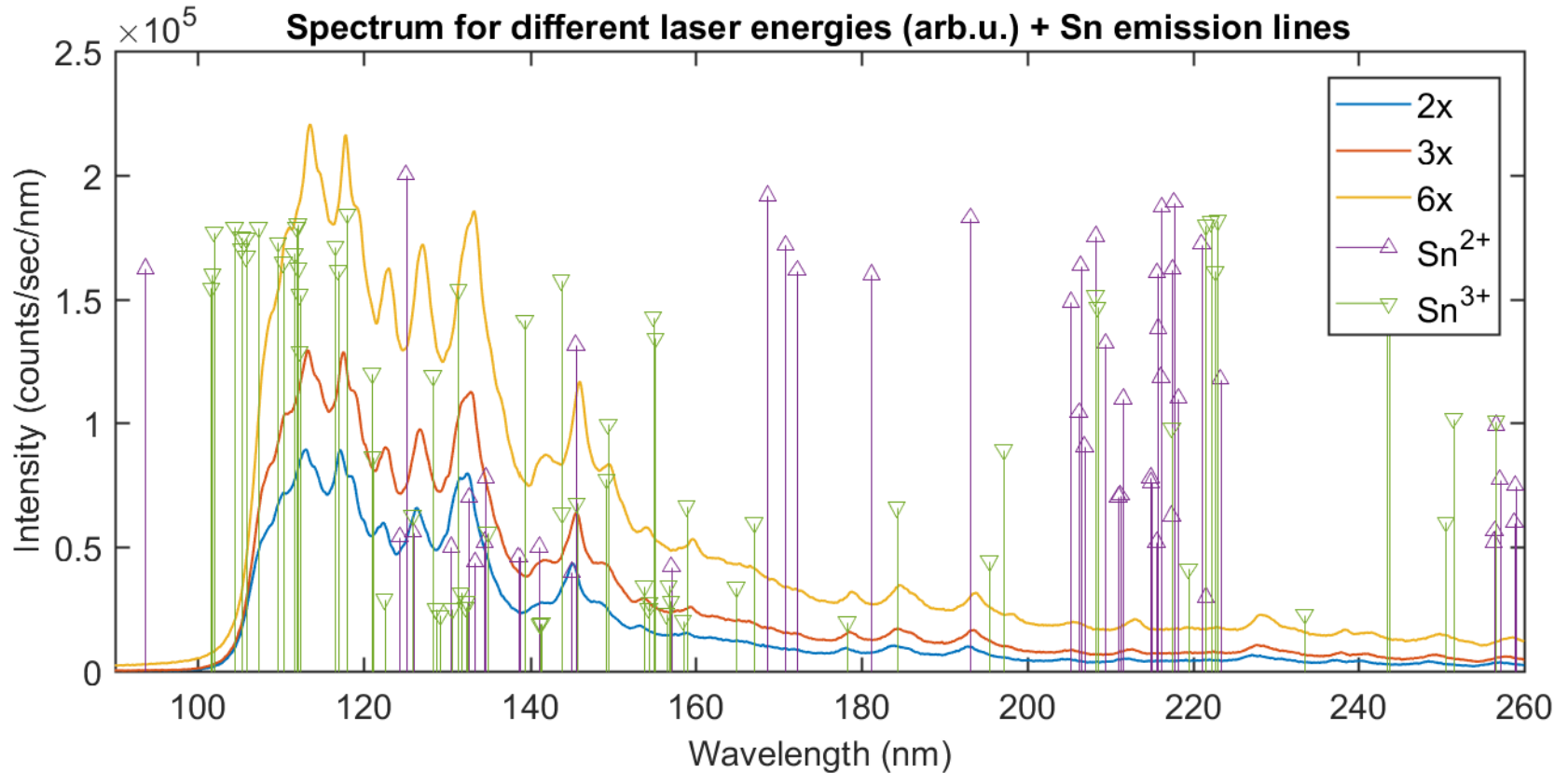
[4] F. Torretti, et.al. ArXiv: 1709.02626 (2017).

Nd:YAG laser plasma: DUV spectra



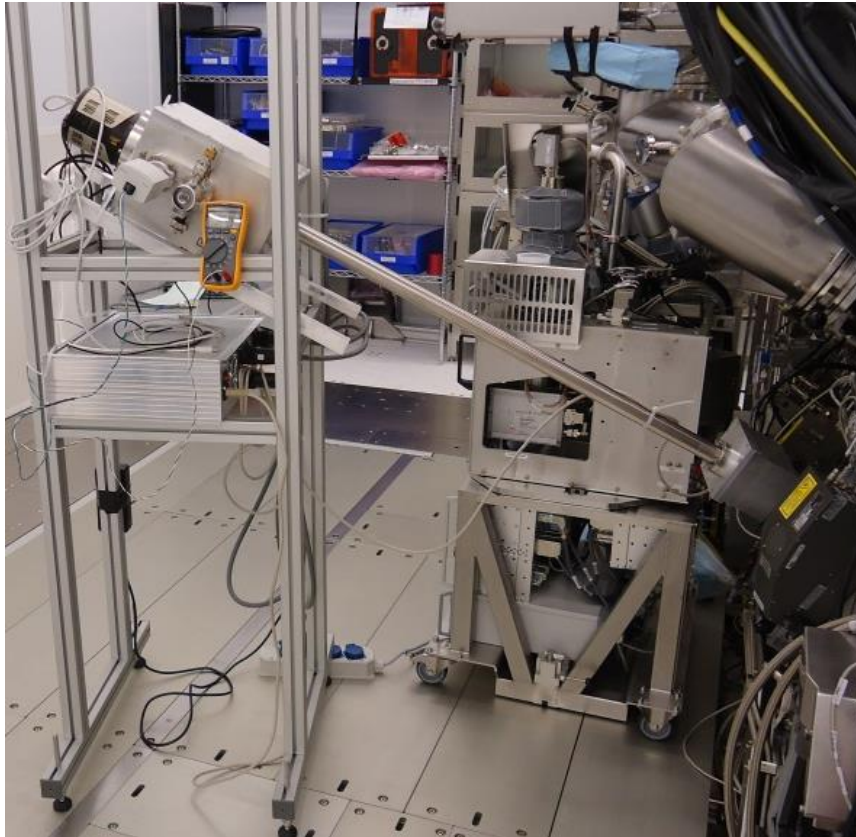
- ✓ DUV spectrum depends on plasma operating conditions
- ✓ Changes in the DUV spectrum can be traced using the spectrometer

Nd:YAG laser plasma: DUV spectra



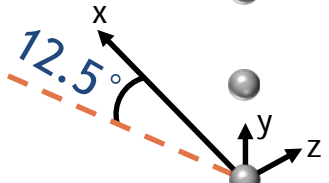
- ✓ Reported Sn^{2+} and Sn^{3+} lines correlate with observed spectrum
- ✓ ARCNL and ISAN collaboration for detailed modeling

Production EUV source



Transmission grating spectrometer

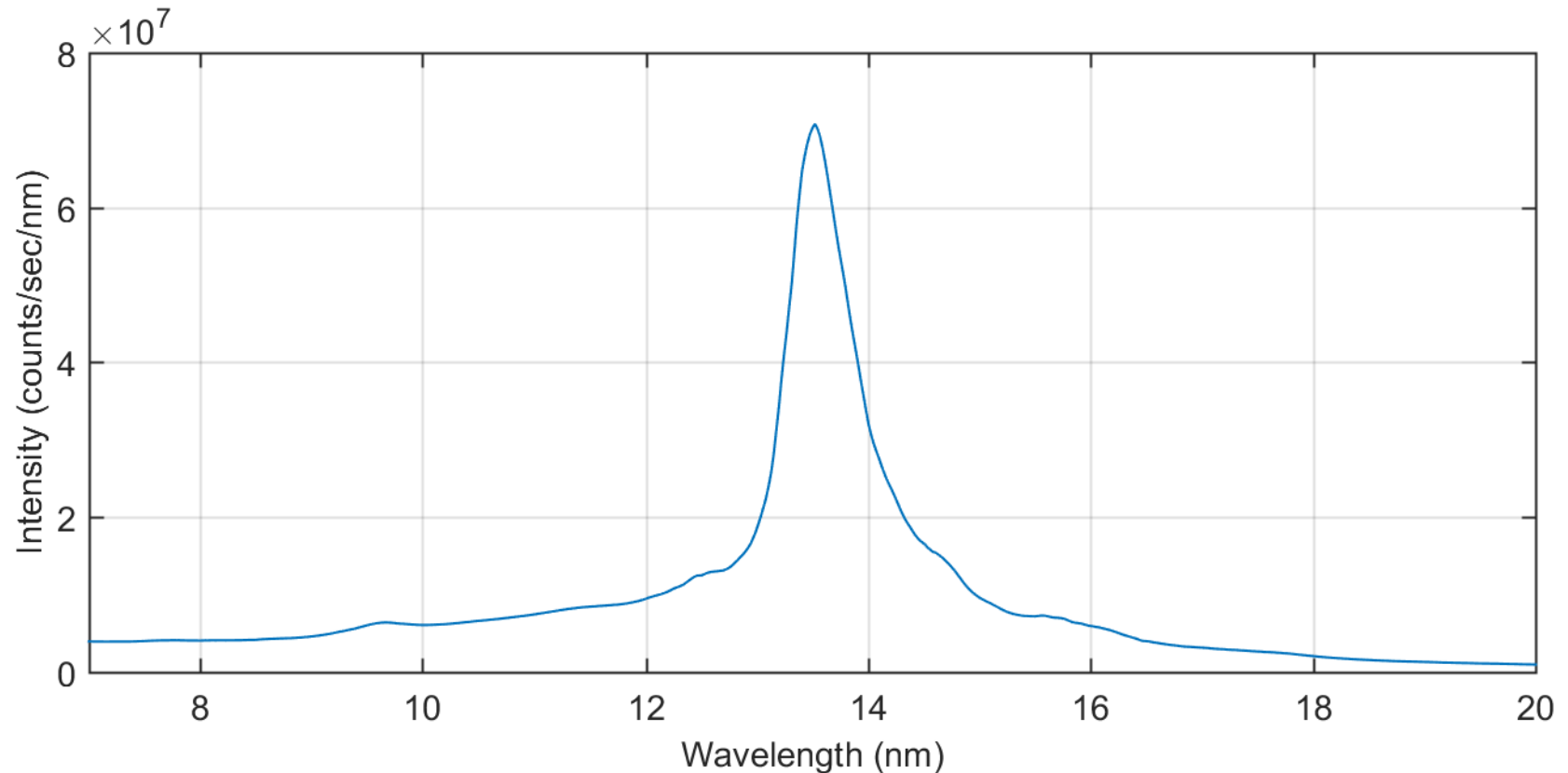
Tin droplets



Drive laser

- ✓ Production EUV light source
- ✓ CO₂ drive laser
- ✓ Real operating conditions!
 - EUV power 120 W

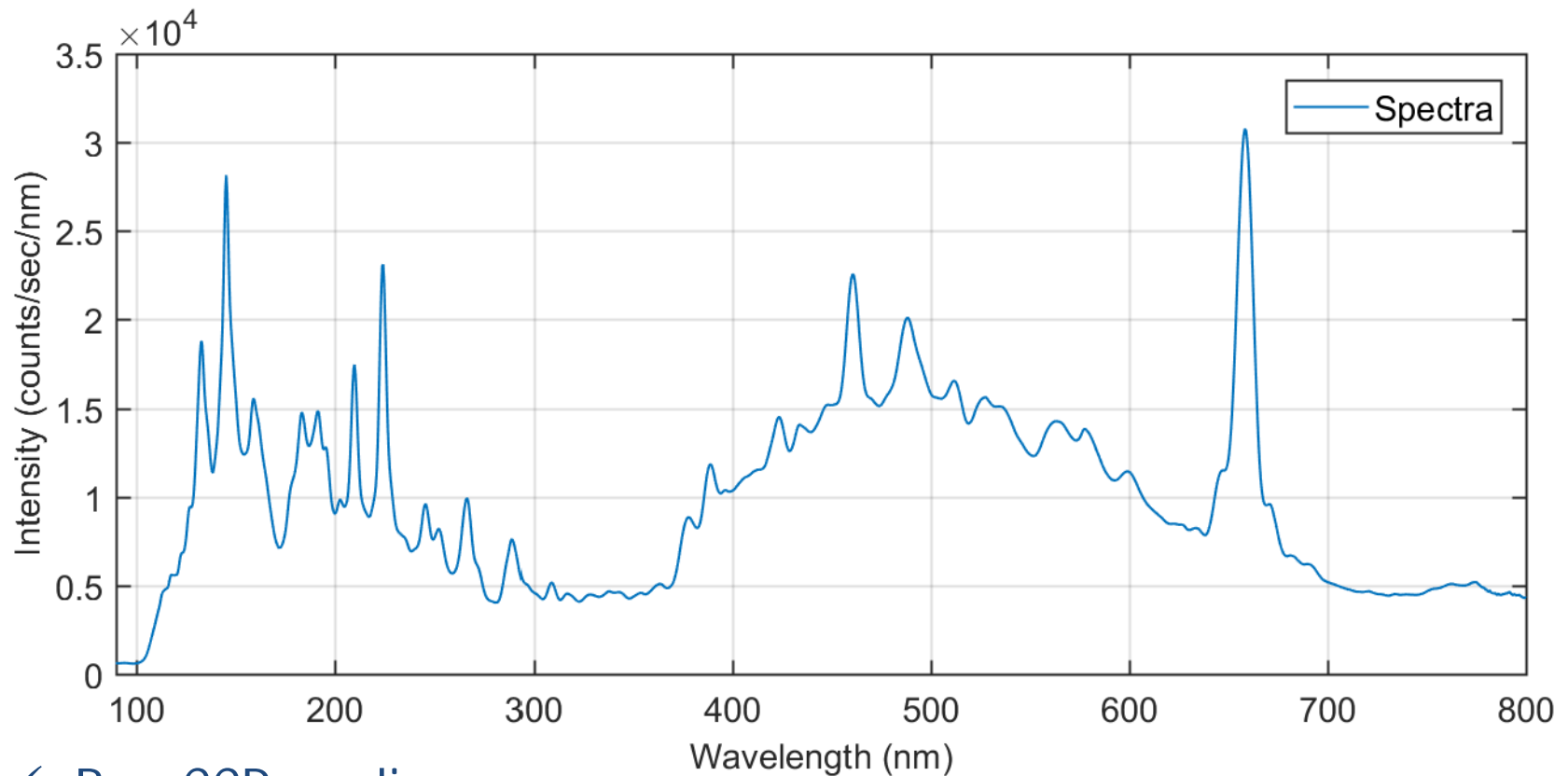
Production EUV source



- ✓ Narrow UTA peak, mainly from Sn^{12+} - Sn^{17+} [5]
- ✓ Intensity at lower wavelengths less pronounced
- ✓ Absolute calibration in progress

[5] K. Nishihara, et.al. Phys. Plasmas 15, 056708 (2008).

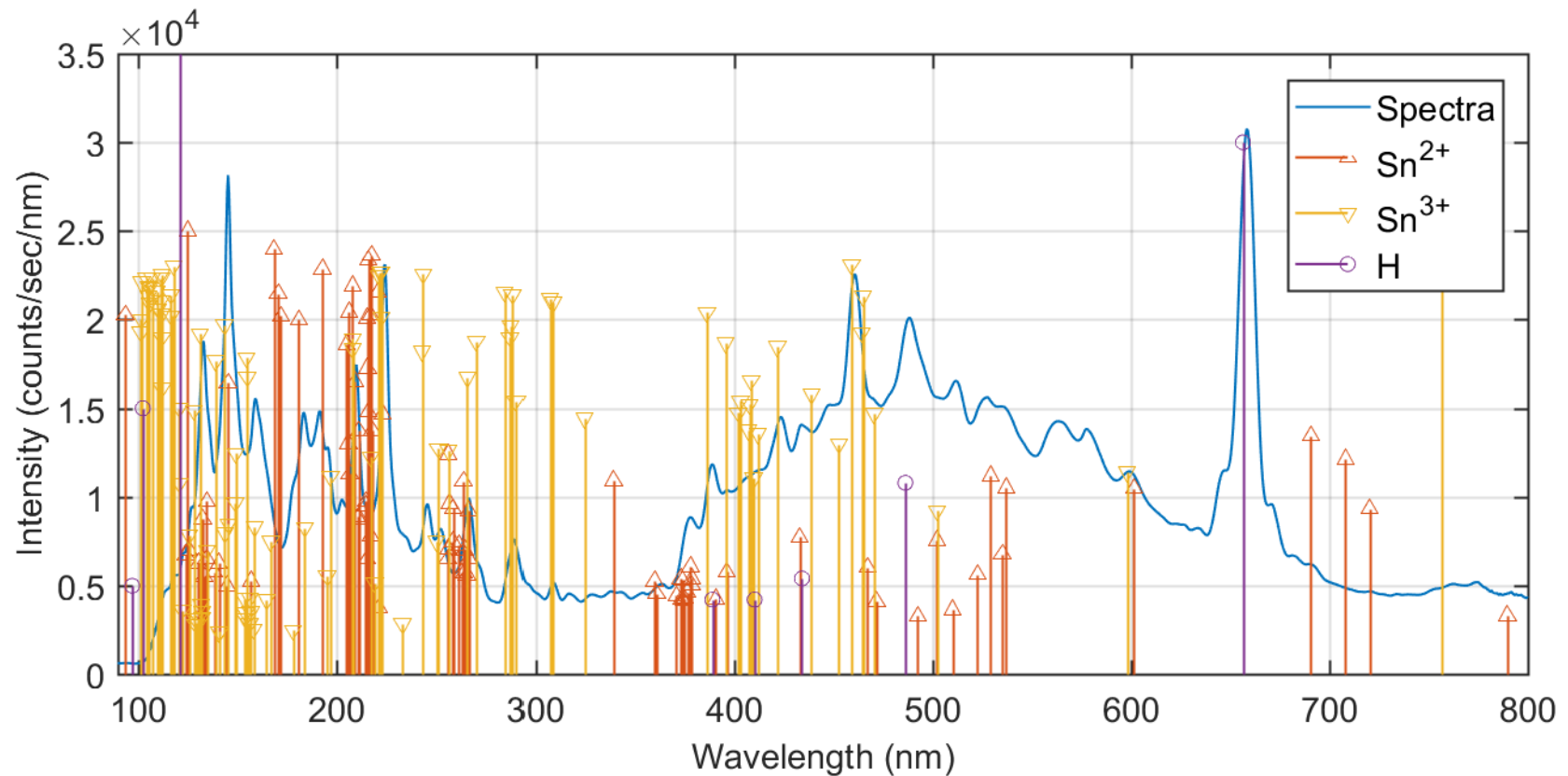
Production EUV source: DUV-NIR spectra



- ✓ Raw CCD readings
- ✓ Low but detectable DUV-NIR intensity
- ✓ Previous knowledge: DUV is ~0.3% of EUV light in resist level^[6]
- ✓ Absolute calibration in progress

[6] N. Davydova, et.al. SPIE, 923102 (2014).

Production EUV source: DUV-NIR spectra



✓ Sn^{2+} , Sn^{3+} and H lines correlate with observed spectra

Conclusion and outlook

- ✓ 1st time spectroscopic measurement in a production EUV source
- ✓ Using a novel transmission grating spectrometer
- ✓ Spectra measured in EUV, DUV-NIR ranges from the same port
- ✓ Emission lines match with reported line positions
 - EUV UTA: Sn^{12+} - Sn^{17+}
 - EUV < 12 nm: Sn^{8+} - Sn^{15+}
 - DUV-NIR: Sn^{2+} - Sn^{3+} and H^+
- ✓ Absolute calibration of spectrometer in progress
- ✓ Detailed plasma modeling will follow from ARCNL and ISAN to complement observed spectra and have a more complete fundamental understanding of the atomic transitions